

EAST - [02952(t:1)]

File View Edit Tools Window Help

☐ Drafts  
☐ Pending  
☒ Active

- L1: (1916) wafer adj5 printed
- L2: (617) recipe and inspect\$4 and mask
- L3: (183310) (step\$4 or setup)adj5 (file or data)
- L4: (9) 11 and 12 and 13**
- L5: (2335) file near9 inspect\$4
- L6: (1) "6388747".pn. and 15
- L7: (138064) load\$4 near9 (data or database)
- L8: (0) "6388747".pn. and 17
- L9: (1) 17 and 14
- L10: (1) 17 and "20030223630".pn.
- L11: (1) load\$4 near9 (data or database or data-base) and 14
- L12: (1) load\$4 near9 (data or database or data-base) and 11 and 12

☐ Failed

Search:    
Default ☒ Highlight all items ready  
11 and 12 and 13

	U	I	Document ID	Iss	Title	Current	Ct
1	<input type="checkbox"/>	<input type="checkbox"/>	US 20040190008	20	Method for process optimization and control by comparison be	356/625	
2	<input type="checkbox"/>	<input type="checkbox"/>	US 20040162687	20	Method and apparatus for self-referenced wafer stage positio	702/85	
3	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040157142	20	Reference wafer and process for manufacturing same	430/22	
4	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030223630	20	Overlay metrology and control method	382/145	
5	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020105649	20	Method and apparatus for self-referenced wafer stage positio	356/401	
6	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020102482	20	Reference wafer and process for manufacturing same	430/22	43
7	<input type="checkbox"/>	<input type="checkbox"/>	US 6734971 B2	20	Method and apparatus for self-referenced wafer stage positio	356/401	
8	<input type="checkbox"/>	<input type="checkbox"/>	US 6699627 B2	20	Reference wafer and process for manufacturing same	430/22	43
9	<input type="checkbox"/>	<input type="checkbox"/>	US 5127726 A	19	Method and apparatus for low angle, high resolution surface	356/237	25

Hit: ☐ Details ☒ HTML

Ready